





ZYGO's most advanced non-contact benchtop surface profiler.



NewView[™] 8000 profiler product highlights

An advanced non-contact 3D metrology tool for surface applications demanding precise quantitative, topographic, volumetric, and texture characterization.

Full 3D visualization of virtually any surface: Topography and texture on rough, polished and highly sloped surfaces—even transparent films

Robust measurements—new technology reveals topography data nearly everywhere there is a feature, even on rough and angled surfaces

Fast—sub-nanometer vertical resolution at high speeds, independent of magnification

The latest edition in the field-proven leader in 3D surface profiling

Newview

Proprietary ZYGO technology enables the NewView 8000 to push beyond the traditional limits of interferometric profilers to provide meaningful height data virtually everywhere there is a sample, even on extremely rough, low reflectivity, and highly sloped surfaces.



The NewView 8000 can analyze process fingerprints such as the post-turning structure of this nickel mirror.

When combined with advanced techniques like SureScan[™] technology, for robust performance even in the presence of vibration, this improved visualization and metrology capability provides an exceptionally powerful platform for surface characterization.



Measure larger objects and highly sloped surfaces, like this US quarter (with over 25 million data points).



Intuitive software

The next standard in metrology software: Mx[™] control and analysis

Max software is ZYGO's all new platform for instrument control and data analysis. Using a simple workflow based concept, users easily navigate the metrology experience from setup through analysis and reporting.

Interactive and detailed plots show full 2D or 3D data; profile slices, material ratio, slope analysis, and PSD views. With built-in SPC, pass/fail indication, data reporting and run charts, production quality analysis is simple.



ADVANCED ANALYSIS

Regions analysis

Regions analysis demonstrates the power of area measurements. In an individual data set, whether from a single field of view or stitched as a composite, regions that are separated laterally and/or vertically can be compared.



AUTOMATION

Stitching and patterned sampling

Stitching is a way of enlarging a field of view and increasing data density. With a motorized XY stage, adjacent fields-ofview are matched at their edges, and joined together into a larger image.

Pattern sampling uses Mx software capabilities of stage programming and data acquisition with automated stages. Stitching and pattern sampling require motorized staging options. **Stitching** with the NewView[™] 8000 profiler allows you to explore surfaces at high magnification with high data density.



Pattern sampling is measuring different locations on the stage, such as a tray of samples or evaluating different areas on a larger object.



The Stitching Preview eliminates stitching grid guesswork



Automated sampling at each location results in multiple measurements from one loading of the stage



Features

- Multiple data collection techniques provide maximum application flexibility for surface heights from angstroms to millimeters
- SureScan[™] technology enables precision metrology in vibration-prone environments
- Correlation to 2D and 3D standards with ISO 25178 compliance
- New streamlined Mx[™] software
- Built in pass/fail, SPC, reporting, & statistics
- Maximum scan rates: 96 μm/sec (NewView 8300); 34 μm/sec (NewView 8200)
- Available built in vibration isolation
- Open structure provides clear part visibility and access
- Large work volume (H x W x D)
- 89 x 150 x 150 mm (standard system)
- 265 x 150 x 150 mm (system w/ optional 176 mm riser kit)
- Larger samples possible by using built in 75 mm head riser and by exceeding the accessible area of the sample stage
- Optional films topography for transparent films > 400 nm thick
- Optional 2D analysis Vision Software Suite

Performance

Surface Topography Repeatability

0.12 nm for all magnifications

Repeatability of the RMS

- 0.01 nm
- Field of view
- From 16 \times 16 mm to 40 \times 40 μ m

Sample Stage

- Manual XY: 100 mm travel
- Motorized XY: 150 mm XY travel
- Tilt: +/- 4° tilt

System Options

- Manual, motorized, and encoded stage options
- Single changeable zoom lens or motorized three position zoom options
- 4 position objective turret
- 35 mm and 176 mm riser kits
- Workstation desk with USB hub
- Instrument stand with seismic restraint locations

Physical Characteristics Dimensions (H × W × D)

- $75 \times 64 \times 56$ cm (benchtop mainframe)
- 151 × 73 × 61 cm (with stand)

System Weight

- 91 kg benchtop configuration
- 229 kg with stand configuration

Flexible Configurations



Objectives

ZYGO maintains the largest selection of interferometric objectives among available optical surface profilers, with standard working distances up to 40 mm and custom configurations in excess of 50 mm. Available objectives include:

- Standard working distance objectives from 1× to 100× magnification. Our 100× objective with 0.85 NA has the finest optical resolution of any interferometric profiler.
- Long working distance (LWD), and super long working distance (SLWD) objectives from 1× to 10× magnification.
- Specialized glass compensated (GC) objectives enable sample observation through a transmissive window.

Gantry Risers

Optional 35 mm (1.3 in.) and 176 mm (6.9 in.) base riser kits work with the included 75 mm head riser to increase standard work volume by more than 9 inches, to enable access to very large parts and deeply recessed surfaces.

Software

Additionally, optional software licenses for vision analysis and transparent films analysis enable multifunctional tool use for a wider variety of applications such as materials characterization, precision machining, prosthetics, MEMS, semiconductor, consumer electro-optics, and optical surface manufacturing.

Largest selection of objectives available in optical metrology

Objective Working Distance (mm)

Magnification	1×	2 ×	2.5×	2.75×	5×	5.5×	10×	20 ×	50×	100×
Michelson/Mirau Standard working distance	-	-	-	4.5	-	8.0	7.4	4.7	3.4	0.5
Long Working Distance	8.0	21.0	-	-	21.0	-	19.0	-	-	-
Super-Long Working Distance	40.0	-	40.0	-	40.0	-	-	-	-	-
Glass Compensated	-	18.5	-	-	19.0	-	18.0	-	-	-

Accessorize your NewView 8000 Profiler

Accessory	Description						
Workstation	 Side desk designed to complement the system and accommodate the monitor, keyboard, mouse and joystick pendant Convenience drawer for storage and USB hub for access to the PC (typically located in the NewView 8000 instrument stand) 						
Objective turret	 4 position, motorized and encoded Various objective mounting and parfocal adapters available 						
Calibration standards	 Step-height: 1.8 µm and 25 µm SiC Reference Flat: choice of 30 mm and 50 mm diameter Lateral: Standard and high-precision versions 						
Gantry risers	35 mm and 176 mm riser kits						





ZYGO CORPORATION Laurel Brook Road Middlefield, Connecticut 06455 Voice: 860 347-8506 www.zygo.com • inquire@zygo.com

©2015 Zygo Corporation. Data subject to change without notice. Covered by US and foreign patents. ZYGO, and the ZYGO logo, are registered trademarks of Zygo Corporation. NewView 8000, SureScan and Mx are trademarks of Zygo Corporation. SB-0347B 1815

THIS DOCUMENT AND THE INFORMATION CONTAINED IN IT OR DISCLOSED BY IT ARE THE PROPERTY OF ZYGO CORPORATION AND ARE ISSUED IN STRICT CONFIDENCE TO THE INTENDED RECIPIENT ONLY. ALL REPRODUCTION AND DISTRIBUTION RIGHTS ARE RESERVED BY ZYGO CORPORATION.